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(54) Title: SUBSTRATE PROCESSING APPARATUS AND METHOD

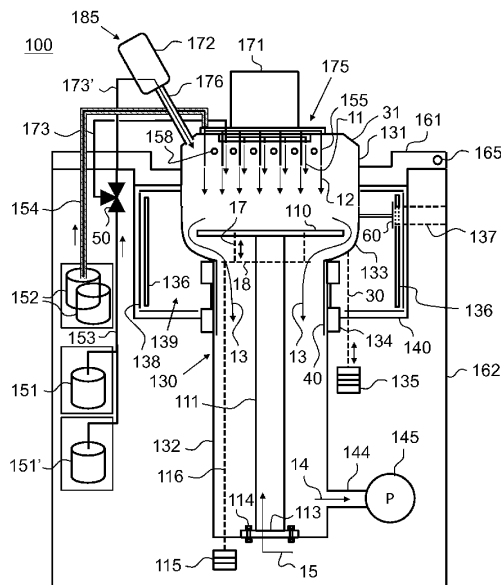


Fig. 1

(57) Abstract: A substrate processing apparatus comprising an inner chamber formed by an upper portion and a lower portion, a substrate support to support a substrate within the upper portion of the inner chamber, a plasma system to provide the inner chamber with plasma species from the top side of the inner chamber, and an outer chamber surrounding the upper portion of the inner chamber. The lower portion of the inner chamber extends to the outside of the outer chamber and remains uncovered by the outer chamber.

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